



Application No. Applicant(s) 09/093,291 Van Buskirk et al. Notice of References Cited Examiner Group Art Unit Allan Olsen 1746 Page 1 of 1 **U.S. PATENT DOCUMENTS** DOCUMENT NO. DATE NAME CLASS SUBCLASS 6,018,065 1/2000 Baum et al. 556 136 Α х В С D E F G н ı J K L М **FOREIGN PATENT DOCUMENTS** CLASS SUBCLASS DOCUMENT NO. COUNTRY NAME DATE N 0 Q R s т **NON-PATENT DOCUMENTS** DOCUMENT (Including Author, Title, Source, and Pertinent Pages) DATE Floy I. Chang et al., Gas-Phase Silicon Micrmachining with Xenon Difluoride, Proc. of SPIE vol.2641, pp 117-128 12/1995 w X

^{*} A copy of this reference is not being furnished with this Office action. (See Manual of Patent Examining Procedure, Section 707.05(a).)